



35.C13974

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PATENT APPLICATION

TECHNOLOGY CENTER 2800

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
: Examiner: D. Monbleau
TADAHIRO OHMI, ET AL.)
: Group Art Unit: 2881
Application No.: 09/425,015)
: Filed: October 25, 1999)
: For: GAS SUPPLY PATH)
STRUCTURE, GAS SUPPLY :
METHOD, LASER OSCILLATING)
APPARATUS, EXPOSURE :
APPARATUS, AND DEVICE)
PRODUCTION METHOD : October 31, 2001

Commissioner for Patents
Washington, D.C. 20231

RESPONSE TO RESTRICTION REQUIREMENT

Sir:

This paper is filed in response to the Restriction Requirement dated
September 7, 2001, requiring Applicants to elect one of the following groups of claims:

Group I: Group I (Claims 1-40), directed to a laser oscillating apparatus;
and

Group II: Group II (Claims 41-44), directed to an exposure apparatus.